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PATENT
03345-P0047A WWW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants	Markus Schwambera, <i>et al.</i>
Serial No. 10/754,817	Filing Date: January 9, 2004
Title of Application:	Process Chamber with a Base with Sectionally Different Rotational Drive and Layer Deposition Method in Such a Process Chamber
Confirmation No. 1549	Art Unit: 1762
Examiner	

Commissioner for Patents
Post Office Box 1450
Alexandria, VA 22313-1450

Information Disclosure Statement by Applicants

As a means of complying with the duty of disclosure set forth in 37 CFR §1.56, Applicants list the following references (copies of the listed patents and papers enclosed).

U.S. Patent Documents				
Exam. Initials	Class/ Subclass.	Document No.	Date	Name
	118/500	4,860,687	8/1989	Frijlink
	118/730	5,788,777	8/1998	Burk, Jr.

Mailing Certificate: I hereby certify that this correspondence is today being deposited with the U.S. Postal Service as *First Class Mail* in an envelope addressed to: Commissioner of Patents and Trademarks; Post Office Box 1450; Alexandria, VA 22313-1450.

July 9, 2004



Gregory D. Venuto

Other Documents	
Exam. Initials	Description (Author, Title, Date, Pages, etc)
	P.M. Frijlink, A New Versatile, Large Size Movpe Recator, (P.M. Frijlink, Journal of Crystal Growth, Nov/Dec. 1988 Nos. 1-4 pp. 207-215.
	P.M. Frijlink, J.L. Nicolas and P. Suchet (Layer Uniformity In A Multwafer MOVPE Reactor for III-V Compounds, Journal of Crystal Growth, 1991, January 1, Nos. 1-4 pp. 166-174.

The listed patents pertain in a general way to the subject matter of the application, but are not necessarily considered to be analogous prior art.

Respectfully submitted,

July 9, 2004



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